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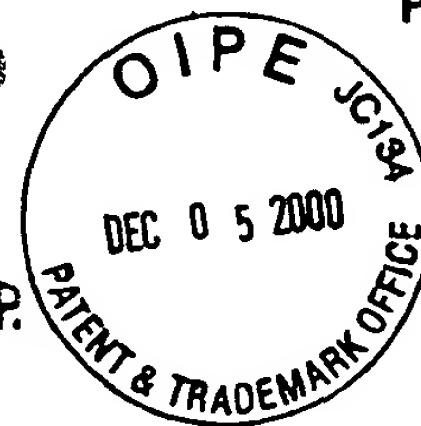
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Two Palo Alto Sq
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OFFICE OF PETITIONS
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In re Reissue Application of
Meisburger et al.
Reissue Application No. 09/502,534
Filed: February 10, 2000
Original Patent No. 5,717,204
Issue Date: February 10, 1998
For: INSPECTING OPTICAL MASKS WITH
ELECTRON BEAM MICROSCOPY

DECISION ACCORDING
STATUS

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TECHNOLOGY CENTER 2800

This is a decision on the petition under 37 CFR 1.47(a) filed October 2, 2000.

The petition is granted.

The above-identified application and papers have been reviewed and found in compliance with 37 CFR 1.47(a). This reissue application is hereby accorded Rule 1.47(a) status.

As provided in Rule 1.47(a), this Office will forward notice of this application's filing to the non-signing inventor at the address given in the Declaration. Notice of the filing of this reissue application will also be published in the Official Gazette.

To expedite the examination in progress, this reissue file is being forwarded to Technology Center AU 2878. **It is noted that the declarations filed with the petition lack compliance with 35 USC 115 and 37 CFR 1.63(a)(3) as they lack the citizenship of every named inventor, e.g., Mr. Meisburger and Mr. Emge. AS THIS IS A REQUIREMENT OF STATUTE NOT SUBJECT TO WAIVER, CORRECTED SUPPLEMENTAL REISSUE DECLARATIONS SHOULD BE FILED PROMPTLY OR WHEN REQUIRED BY THE EXAMINER.**

Telephone inquiries related to this decision should be directed to the undersigned at (703) 305-1820.

Brian Hearn
Petitions Examiner
Office of Petitions
Office of the Deputy Commissioner
for Patent Examination Policy

Enclosure: Corrected Filing Receipt



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DAN MEISBURGER
1507 MONTALBAN DRIVE
SAN JOSE CA 95120-4830

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LETTER

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Dear Mr. Meisburger:

You are named as a joint inventor in the above-identified United States patent application, filed under the provisions of 35 U.S.C. 116 (United States Code), and 37 CFR 1.47(a), Rules of Practice in Patent Cases. Should a patent be granted on the application you will be designated therein as a joint inventor.

As a named inventor you are entitled to inspect any paper in the file wrapper of the application, order copies of all or any part thereof (at a prepaid cost per 37 CFR 1.19) or make your position of record in the application. Alternatively, you may arrange to do any of the preceding through a registered patent attorney or agent presenting written authorization from you. If you care to join the application, counsel of record (see below) would presumably assist you. Joining in the application would entail the filing of an appropriate oath or declaration by you pursuant to 37 CFR 1.63.

Inquiries related to this communication may be addressed to the undersigned at (703) 305-1820. Requests for information regarding your application should be directed to the File Information Unit at (703) 308-2733. Information regarding how to pay for and order a copy of the application, or a specific paper in the application, should be directed to Certification Division at (703) 308-9726 or 1 (800) 972-6382 (outside the Washington D.C. area).

Brian Hearn
Petitions Examiner
Office of Petitions
Office of the Assistant Commissioner
for Patent Examination Policy

cc:
Fenwick & West LLP
Two Palo Alto Sq
Palo Alto, CA 94306